

JC986 U.S. PTO
10/082567
02/25/02

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10082567	FILING DATE 02 25 2002	CLASS 430	SUBCLASS	GAU 2012	EXAMINER
**APPLICANTS: Tse Ten, Zhao Zhiyong, Hendrix David.					
**CONTINUING DATA VERIFIED:					
** FOREIGN APPLICATIONS VERIFIED:					
PG-PUB		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no verified and Acknowledged Examiner's initials				ATTORNEY DOCKET NO 1458 TT4763	
TITLE : Method and system for dose control during an ion implantation process					

NOTICE OF ALLOWANCE MAILED		Assistant Examiner		CLAIMS ALLOWED	
				Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner		DRAWING	
Amount Due	Date Paid			Sheets Drwg.	Figs.Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE		Application Examiner	
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